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Amendments to the Claims:

This listing of claims replaces all prior versions and listings of claims in the application:

Listing of Claims:

Amendments to the Claims

- 1. (Currently Amended) An apparatus for forming a film comprising:
- a load chamber:
- a conveyance chamber connected to the load chamber; and
- a film formation chamber connected to the conveyance chamber.
- wherein the film formation chamber comprises a first evaporation source, means that moves the first evaporation source, a second evaporation source, means that moves the second evaporation source, a third evaporation source, and means that moves the third evaporation source, and

wherein the first, second, and third evaporation sources are movable in an X direction, a Y direction, and a Z direction in the film formation chamber.

- 2. (Previously Presented) The apparatus for forming the film according to claim 1, wherein an installation chamber is connected to the film formation chamber, and wherein the installation chamber is connected to evacuating and exhausting means that evacuates the installation chamber and has a mechanism for setting an evaporation material in the first, second, and third evaporation sources in the installation chamber.
- 3. (Previously Presented) The apparatus for forming the film according to claim 1, wherein the film formation chamber is connected to an evacuation and exhaust treatment chamber that evacuates the film forming chamber and has means for introducing at least one of a material gas and a cleaning gas.

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4. (Canceled)

- (Previously Presented) The apparatus for forming the film according to claim 1, wherein the film formation chamber has a shutter that sections the film formation chamber and shields evaporation to the substrate.
- 6. (Previously Presented) The apparatus for forming the film according to claim 1, wherein a sealing chamber is connected to the conveyance chamber, and wherein the sealing chamber is connected to evacuating and exhausting means, which evacuates the sealing chamber, and has a mechanism for applying a seal material with an ink jet method in the sealing chamber.
 - 7. (Currently Amended) An apparatus for forming a film comprising:
 - a load chamber;
 - a conveyance chamber connected to the load chamber; and
 - a film formation chamber connected to the conveyance chamber,

wherein the film formation chamber comprises an aligning means that aligns a mask and a substrate, a first evaporation source, means that moves the first evaporation source, a second evaporation source, means that moves the second evaporation source, a third evaporation source, and means that moves the third evaporation source, and

wherein the first, second, and third evaporation sources are movable in an X direction, a Y direction, and a Z direction in the film formation chamber.

8. (Previously Presented) The apparatus for forming the film according to claim 7, wherein an installation chamber is connected to the film formation chamber, and wherein the installation chamber is connected to evacuating and exhausting means that evacuates the installation chamber and has a mechanism for setting an evaporation material in the first, second, and third evaporation sources in the installation chamber.

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9. (Previously Presented) The apparatus for forming the film according to claim 7.

wherein the film formation chamber is connected to an evacuation and exhaust treatment chamber that evacuates the film forming chamber and has means for introducing at least one of a material gas and a cleaning gas.

10. (Canceled)

- 11. (Previously Presented) The apparatus for forming the film according to claim 7, wherein the film formation chamber has a shutter that sections the film formation chamber and shields evaporation to the substrate.
- 12. (Previously Presented) The apparatus for forming the film according to claim 7, wherein a sealing chamber is connected to the conveyance chamber, and wherein the sealing chamber is connected to evacuating and exhausting means, which evacuates the sealing chamber, and has a mechanism for applying a seal material with an ink jet method in the sealing chamber.
 - 13. (Currently Amended) An apparatus for forming a film comprising:
 - a load chamber;
 - a conveyance chamber connected to the load chamber; and
 - a film formation chamber connected to the conveyance chamber,

wherein the film formation chamber comprises a first evaporation source, means that moves the first evaporation source, a second evaporation source, means that moves the second evaporation source, a third evaporation source, and means that moves the third evaporation source, [[and]]

wherein the first, second third evaporation sources have containers with elliptical openings, and

wherein the first, second, and third evaporation sources are movable in an X direction, a Y direction, and a Z direction in the film formation chamber.

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14. (Previously Presented) The apparatus for forming the film according to claim 13, wherein an installation chamber is connected to the film formation chamber, and wherein the installation chamber is connected to evacuating and exhausting means that evacuates the installation chamber and has a mechanism for setting an evaporation material in the first, second, and third evaporation sources in the installation chamber.

15. (Previously Presented) The apparatus for forming the film according to claim 13, wherein the film formation chamber is connected to an evacuation and exhaust treatment chamber that evacuates the film forming chamber and has means for introducing at least one of a material gas and a cleaning gas.

16. (Canceled)

17. (Previously Presented) The apparatus for forming the film according to claim 13, wherein the film formation chamber has a shutter that sections the film formation chamber and shields evaporation to the substrate.

18. (Previously Presented) The apparatus for forming the film according to claim 13, wherein a scaling chamber is connected to the conveyance chamber, and wherein the scaling chamber is connected to evacuating and exhausting means, which evacuates the scaling chamber, and has a mechanism for applying a seal material with an ink jet method in the scaling chamber.

(Currently Amended) An apparatus for forming a film comprising:
a load chamber;

a conveyance chamber connected to the load chamber; and

a film formation chamber connected to the conveyance chamber,

wherein the film formation chamber comprises a first evaporation source, means that moves the first evaporation source, a second evaporation source, means that moves the second Applicant : Shunnei Yamazaki et al. Attorney's Docket No.: 12732-228001 / US7116

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evaporation source, a third evaporation source, and means that moves the third evaporation source, [[and]]

wherein the first, second third evaporation sources have containers with inclined openings, and

wherein the first, second, and third evaporation sources are movable in an X direction, a Y direction, and a Z direction in the film formation chamber.

- 20. (Previously Presented) The apparatus for forming the film according to claim 19. wherein an installation chamber is connected to the film formation chamber, and wherein the installation chamber is connected to evacuating and exhausting means that evacuates the installation chamber and has a mechanism for setting an evaporation material in the first, second, and third evaporation sources in the installation chamber.
- (Previously Presented) The apparatus for forming the film according to claim 19. wherein the film formation chamber is connected to an evacuation and exhaust treatment chamber that evacuates the film forming chamber and has means for introducing at least one of a material gas and a cleaning gas.
 - 22. (Canceled)
- 23. (Previously Presented) The apparatus for forming the film according to claim 19. wherein the film formation chamber has a shutter that sections the film formation chamber and shields evaporation to the substrate.
- 24. (Previously Presented) The apparatus for forming the film according to claim 19. wherein a sealing chamber is connected to the conveyance chamber, and wherein the sealing chamber is connected to evacuating and exhausting means, which evacuates the sealing chamber, and has a mechanism for applying a seal material with an ink jet method in the scaling chamber.

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25. (Withdrawn) A container for forming a film containing an organic compound by evaporation,

wherein the container has an elliptical opening.

26. (Withdrawn) The container according to claim 25, wherein the container has a prism shape.

 (Withdrawn) A container for forming a film containing an organic compound by evaporation,

wherein the container has an inclined opening.

28. (Withdrawn) The container according to claim 27, wherein the container has a prism shape.